

E4860

Recirculating Heater/Chiller

Suitable for:

The E4860 Recirculating Heater/Chiller is recommended for a wide range of open and closed-loop temperature control applications. The E4860 is the solution for use with the E3100 and K850WM critical point dryers.



The E4860 Heater/Chiller

The E4860 water recirculating heater/chiller is recommended for a wide range of open and closed loop applications, offering simplicity, reliable and quiet operation. A 3-term digital temperature controller ensures ease of use and accuracy; water temperature can be accurately controlled over the range -10 to +60°C.

Features

- Precise temperature control
- Quiet, efficient operation
- Proven reliability



Checking the heater/chiller performance:

To cool or heat any instrument or system it is important to obtain the following information from the manufacturer.

- Heat load to be dissipated to water, e.g. for an SEM/TEM: diffusion pump heater, lenses, etc.
- Flow rate and size of tubing
- Minimum pressure

Flow rate x wt. of fluid x Sp. heat x DT = heat extraction rate (in Watts)

	-20°C	-10°C	0°C	+10°C	+20°C
E4860	75W	105W	180W	300W	420W

E4860 Specifications

Product Specifications	E4860
Extraction rate (Watts) at 20°C	420W
Temperature range (°C)	-20°C to +70°C
Refrigeration (HP)	1/5
Heater rating (kW)	1
Max. pump flow litre/hour	450
Height (cm)	37
Width (cm)	32
Depth (cm)	46
Weight (kg)	40
Water connections	16mm hose or 1/8 BSP

E4860 Options

- High pressure pumps
- Water failure alarms
- Over and under temperature cut-outs



E3500 Thermo-circulator (heating only)

E3500 Thermo-circulator is a low-cost, portable water circulating system for supplying a constant temperature supply for closed and open loop applications at near ambient to +60°C temperature. The E3500 will give controlled heating of the Quorum E3000 and E3100 critical point dryers.

The CPD range from Quorum

E3100

- Simple robust construction
- Horizontal chamber and large viewing window gives excellent visibility of fluid level and drying process
- Robust valves for draining, ingress of CO2 and venting of gas. Helps prevent drying of specimen.
- Optional specimen holders



K850

- Good visibility with a side viewing chamber
- Accurate temperature control due to built in adiabatic cooling and thermoelectric heating
- Enhanced solvent exchange due to built in stirrer
- Thermal cut-out protection
- Safety cut-out for over pressure
- Optional holders for larger specimens and cover-slips



K850WM

- Optimised for wafer and MEMS drying with 170 mm process chamber
- No risk to specimens becoming uncovered due to top loading and bottom draining system
- Accurate temperature control due to thermoelectric heating
- Precise control with fine needle valve pressure let-down
- Thermal cut-out protection
- Safety cut-out for over pressure

